PTO/SB/08 (2-92) Sheet 1 of 1

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	Docket Number 325772020700	Application Number 09/735,608		
	Hirosh	i Hatno		
Filing Date: December 14, 2000		Group Art Unit 2653		
	Examiner Kim Kwok Chu	DECENIED		

N APPLICA	ATION								
(Use several sheets if necessary)			Filing Date: December 14, 2000		Group Art Unit 2653				
Examiner Kim Kwok C			hu	RECE	SIVED				
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U.S. PATENT DOCUMENTS Technology Center 2600									
Date	Document No.	Name	Class	Subclass	Filing Date If Appropriate				
6-12-1945	2,378,301	Edward K Kaprellan	359	731	04-08-1944				
0-16-1962	3,059,113	T.F. McHenry	250	353	05-25-1960				
0-24-1978	4,121,890	Braun	356	4.02	08-17-1977				
1-02-2001	6,169,637	Tsunashima	359	726	05-04-1999				
3-20-1984	4,437,746	lkemori	368	272	03-25-1982				
FOREIGN PATENT DOCUMENTS									
Date	Document No.	Country	Class	Subclass	Translation YES NO				
	OTHER	DOCUMENTS	(including a	author, title, Date,	, Pertinent Pages, Etc.)				
itle 									
REFLECTING MICROOPTICAL SYSTEM, filed November 25, 1999 as U.S. Serial No.: 09/450,271									
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	Date 16-12-1945 10-16-1962 10-24-1978 11-02-2001 103-20-1984 Date Title REFLECTIN	U.S. PAT Date	U.S. PATENT DOCUMENTS Date Document No. Name 16-12-1945 2,378,301 Edward K Kaprellan 10-16-1962 3,059,113 T.F. McHenry 10-24-1978 4,121,890 Braun 11-02-2001 6,169,637 Tsunashima 13-20-1984 4,437,746 Ikemori FOREIGN PATENT DOCUMENT Date Document No. Country OTHER DOCUMENTS Title REFLECTING MICROOPTICAL SYSTEM, filed No.	Filing Date: December 14, 2000	Filing Date: December 14, 2000 Group Art University				

DATE CONSIDERED:

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